Title (en)

LIGHTING MEANS AND METHOD FOR OPERATING SAME

Title (de)

LEUCHTMITTEL UND BETRIEBSVERFAHREN DAFÜR

Title (fr)

LUMINAIRE ET SON PROCÉDÉ DE FONCTIONNEMENT

Publication

EP 2659503 B1 20161221 (DE)

Application

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Abstract (en)

[origin: WO2012095081A1] The invention relates to a lighting means having a gas volume and a coaxial HF-energy injection device for exciting same with surface waves. According to the invention, the coaxial HF-energy injection device (3) comprises a central conductor (4) guided through the gas volume (2).

IPC 8 full level

H01J 65/04 (2006.01)

CPC (source: EP RU US)

H01J 65/042 (2013.01 - RU US); **H01J 65/044** (2013.01 - EP US)

Citation (examination)

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